

# **Magnetic Device Design' and Evaluation Capabilities at JPL**

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# Presentation overview

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- Magnetic device development paradigm.
- Magnetic device design and simulation capabilities at JPL.
- Magnetic device experimentation and observation capabilities at JPL.
- Standardization of magnetic device development tools and processes.
- Potential applications in future space missions.
- Conclusions.

# A Device Development Paradigm

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- Device development uses cycles of design, fabrication, experimentation, and analysis.
- Device design invokes conceptual and calculable design processes, including analytical and simulated calculations, based on available materials, fabrication processes, and test data.
- Experimentation, testing, and characterization are used to demonstrate device performance, and to validate fabrication and design processes.

# JPL Design Capabilities

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- Device Layout.
- Computer simulations:
  - » Magnetic field computation.
  - » Distributed Wall Modeling.
  - » Micromagnetic Modeling.

# Magnetic Device Layout Representation

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- Magnetic Device Layers:

- » Conductors.
- » Insulators and Dielectrics.
- » Vias.
- » Permeable magnetic layers.
- » Magnetoresistors.
- » Permanent magnets.
- » Implantation.
- » Stress Layers.
- » Mirrors.

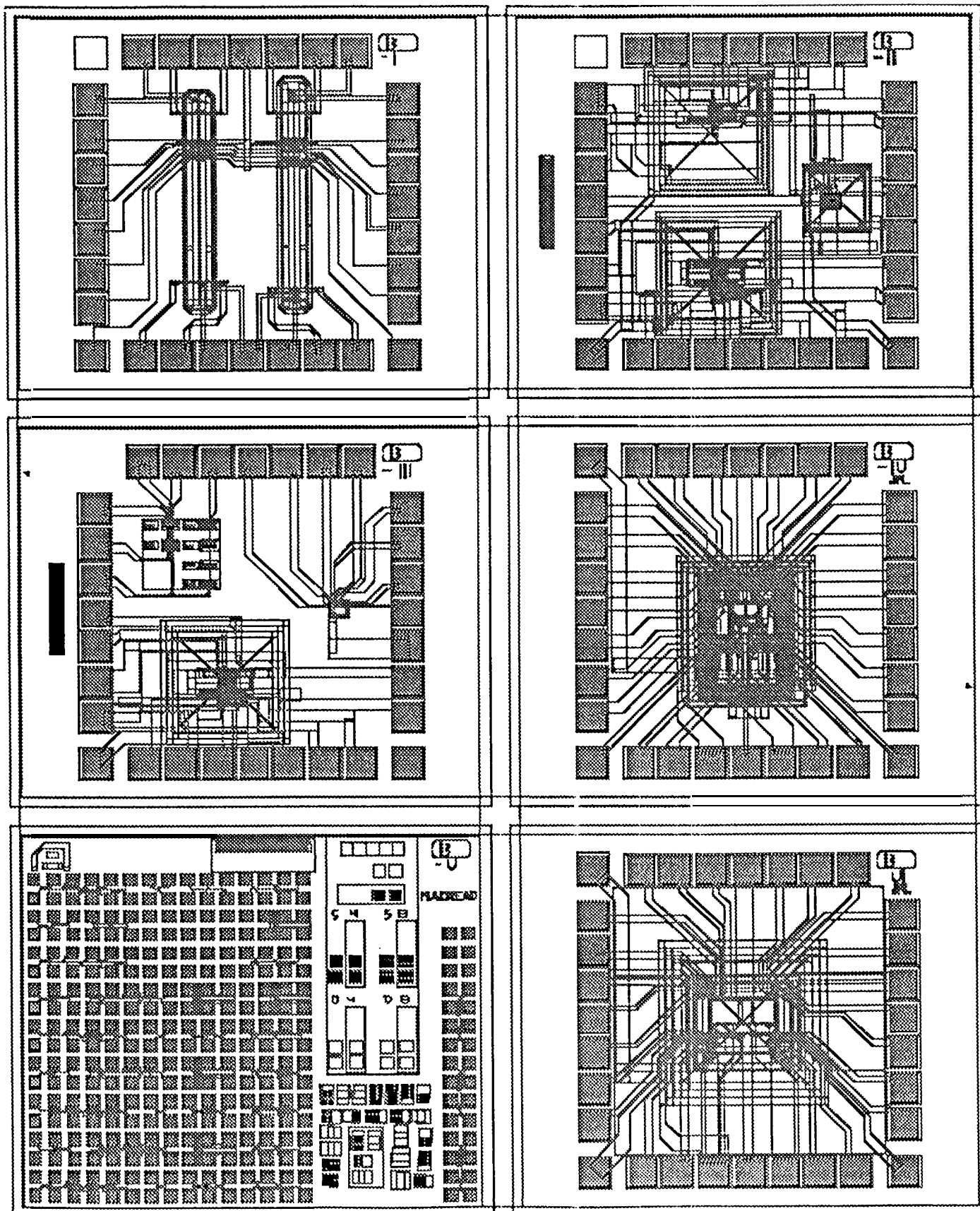
- Output formats:

- » CIF.
- » GDS-II.

Cell: bchip File: BCHIP040795 Date: 11 Apr 95 Tanner Tools L-Edit™/Macintosh

Cell bounds: 153000 x 195000 Units = 7650 x 9750 Microns

This view: 164528 x 217582 Units = 8226 x 10879 Microns



# Magnetic Field Computation

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- Magnetic field computation:
  - » Custom computer programs:
    - Magnetic field induced by currents.
    - Magnetic field induced by magnetization and its divergence.
  - » Commercial software.

# Distributed Wall Model

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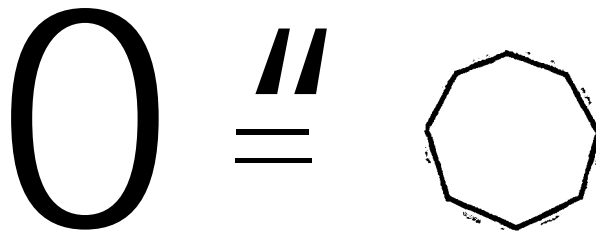
- Simulate static and dynamic domain wall motion in a magnetic material.
- Represent a domain wall by a set of wall points.
- Model material parametrically.
- Apply equation of motion at wall points to determine domain wall dynamics.
- Use on workstations or personal computers to simulate dynamics u. to millimeter dimensions for up to millisecond durations.
- Provide graphical and file-input user interfaces to facilitate initiating, visualizing, and analyzing case studies.



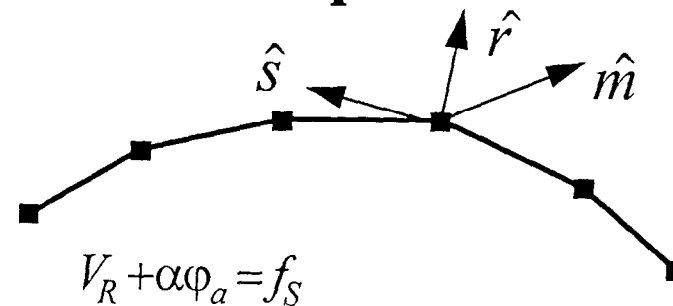
# Micromagnetic Devices Group

## DWM: Overview

- Approximate wall with a polygonal segment.



- Equations of motion for wall points:



$$\alpha V_R - \varphi_a = f_R$$

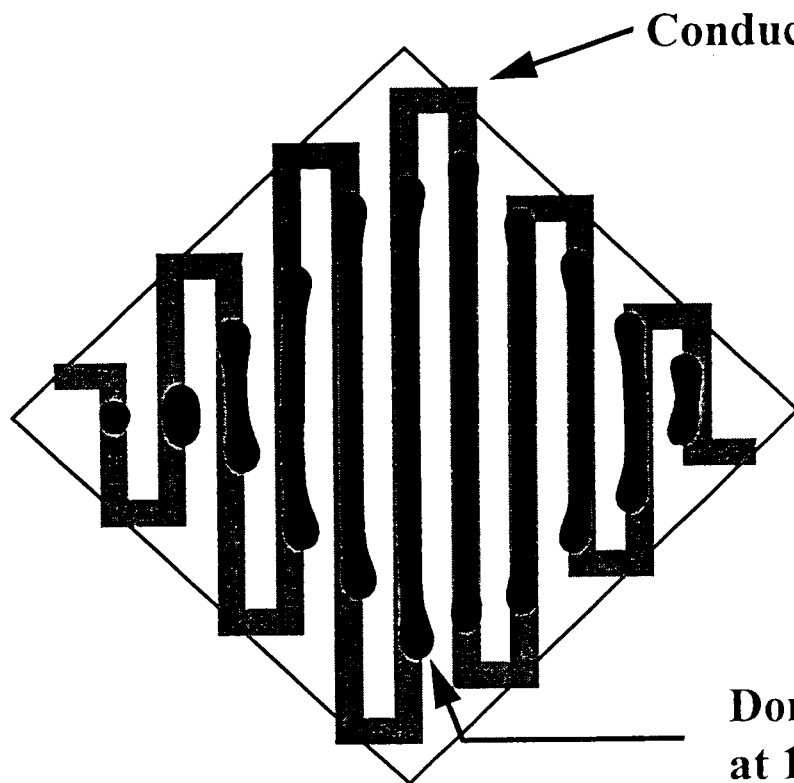
$$f_S = \frac{1}{2} (\sin 2\varphi_w + 2q \frac{\partial^2 \varphi_a}{\partial S^2})$$

$$f_R = -\frac{q}{\rho} - \frac{1}{2} \frac{\partial}{\partial S} \sin 2\varphi_w + (H_D - H_A)$$

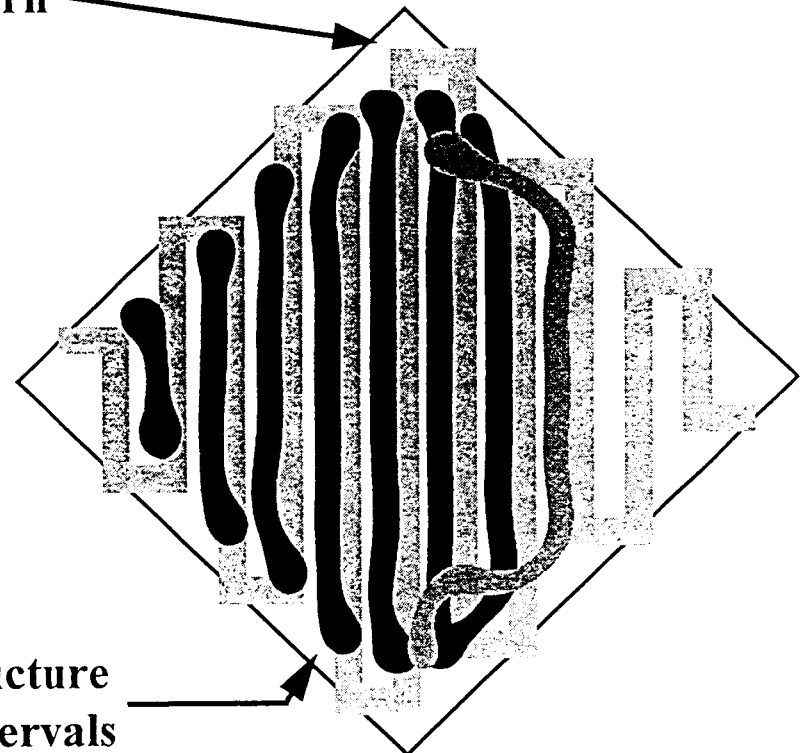
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## Sample DWM Result

Normal Operation of VBL  
Expander/Detector Region



Failure Mode of VBL  
Expander/Detector Region



# Micromagnetics Model

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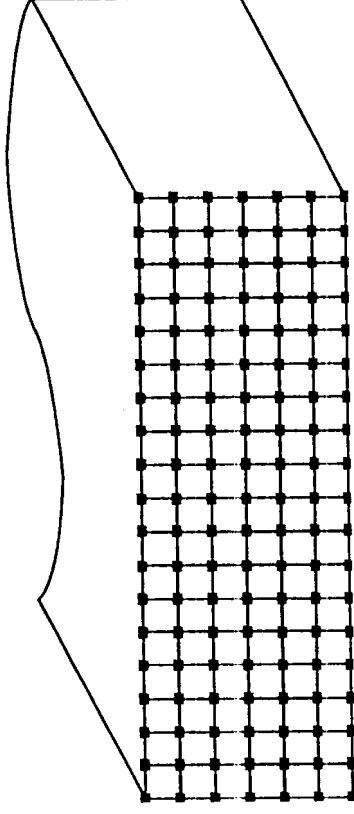
- Simulate statics and dynamics of magnetization in discretized cells in a magnetic material.
- Represent domain wall as a strip of reversing magnetization.
- Solve the Landau-Lifschitz-Gilbert equation of motion locally to determine magnetization dynamics.
- Use on supercomputers to simulate dynamics at submicron nanoscales for submicrosecond durations.
- Provide graphical and file-input user interfaces to facilitate initiating, visualizing, and analyzing case studies.

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## Micromagnetics: Overview



- Low level material modeling which accounts for changes in the magnetization on the order of 10nm.



$$\dot{\hat{m}} = \frac{\gamma}{(1 + \alpha^2)} (H \times \hat{m}) + \alpha (\hat{m} \times (H \times \hat{m}))$$

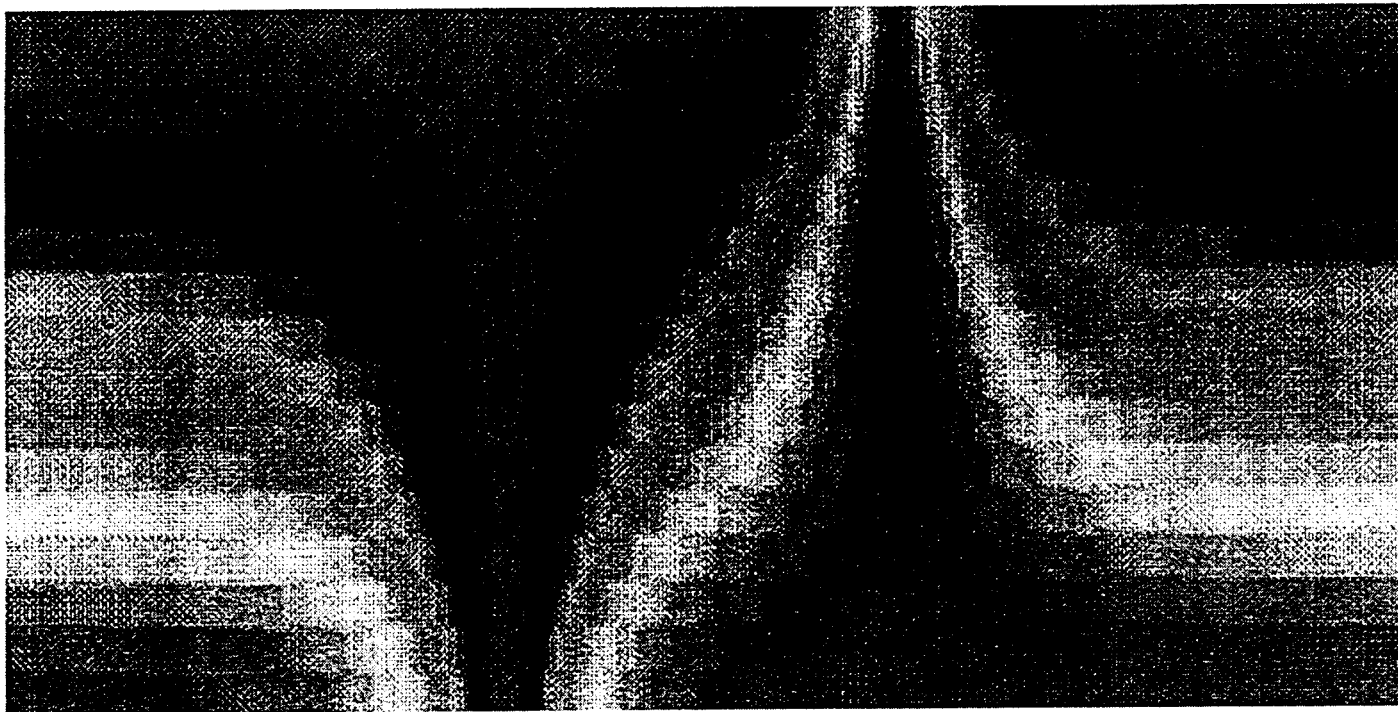
$$H_{\text{total}} = H_{\text{anis}} + H_{\text{exch}} + H_{\text{demag}} + H_{\text{externa}}$$

# Micromagnetic Devices Group

## Sample Micromagnetic Result

### ■ Structure of a $2\pi$ VBL in garnet material.

(color shows component of magnetization perpendicular to wall surface)



# JPL Experimentation Capabilities

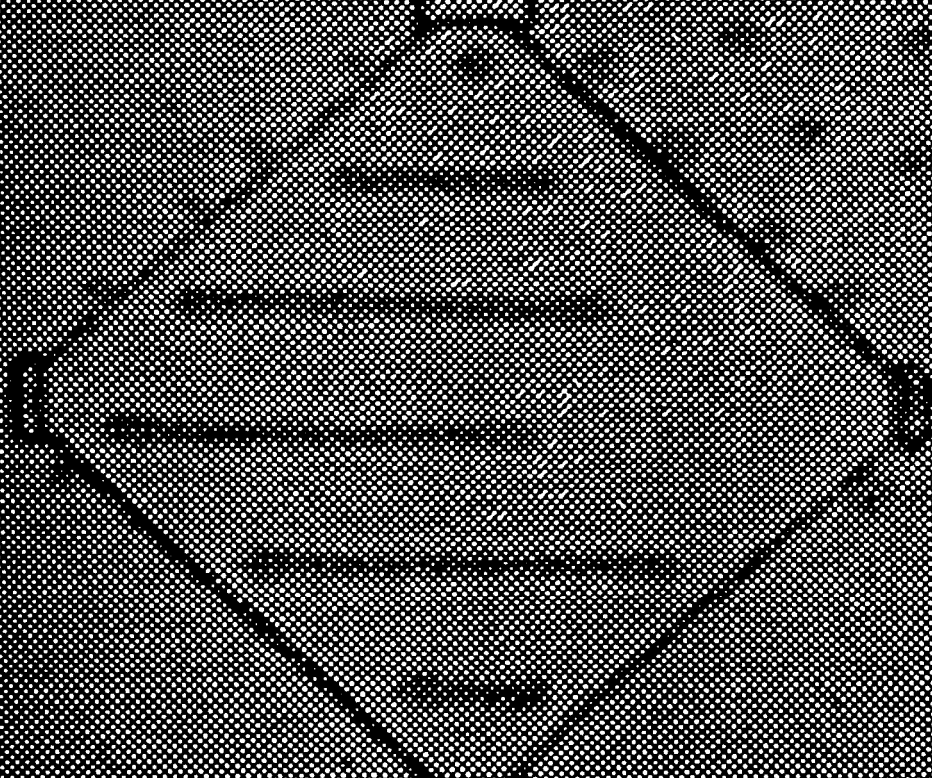
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- Electro-magneto-optic test systems:
  - » Continuous illumination microscopy.
  - » High-resolution sampling microscopy.
- Magnetoresistance characterization system.
- Electrical wafer-level probing systems.
- Logic analyzers.
- Characterization:
  - » SEM, TENV, AFM, XRD, etc.
- Spaceflight Experiments.

# Electro-magneto-optic testing: Continuous illumination

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- Observe domains, domain walls, and domain wall structure in magnetic devices and films in transmission and reflection.
- Observe magnetic domain characteristics statically and through time-averaging, using optical and opto-electronic observation.
- Use continuous illumination to maximize image signal-to-noise ratio:
  - » High photon density.
  - » Signal averaging.
- Operate device subject to a variety of magnetic fields under computer control:
  - » Derive AC and DC fields from on-chip conductors; with in-plane and out-of-plane components.
  - » Derive AC and DC fields from off-chip coils, magnets, and electromagnets; with in-plane and out-of-plane components.



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# Electro-magneto-optic testing: Sampling microscopy

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- Observe domains, domain walls, and domain wall structure in magnetic devices and films in transmission and reflection.
- Observe magnetic domain characteristics in a sampling mode, using optical and opto-electronic observation.
- Use laser stroboscope and image processing to determine repetitive magnetization dynamics with approximately 10 ns event resolution:
  - » Perform flash microscopy using high-power pulse laser and SIT camera.
  - » Use frame grabbing, averaging, and subtraction to observe magnetization dynamics.
- Operate device subject to a variety of magnetic fields under computer control:
  - » Derive AC and DC fields from on-chip conductors; with k-plane and out-of-plane components.
  - » Derive AC and DC fields from off-chip coils, magnets, and electromagnets; with in-plane and out-of-plane components.

Video Monitor

Hamamatsu  
C2400 SIT  
camera

PC Comparable  
Computer

National Instruments  
AT-DIO32 Digital I/O

National Instruments  
AT-GPIB

32 Digital I/O lines  
and Handshake

GPIB Bu

Video out

Hamamatsu DVS3000  
Image Processor

Video in

V<sub>out</sub> Camera  
Hamamatsu  
C2400 Camera control

V<sub>sync</sub>

Current  
Shunt

HP 6038A DC Power  
Supply @ias field)

Current  
Shunt

HP 6038A DC Power  
Supply (In-Plane field)

Polarizing  
Optical  
Microscope

Eyepiece

Analyzer

Objective

Bias Coil  
In-Plane Coil  
Memory  
Chip

14 I/O Pins per device

Polarizing  
Condenser

Optical Fiber

Dye  
Laser

Sopra Flowing Nitrogen  
Ultraviolet laser

Trig

GPIB

SRS DG535  
2ch pulse generator

GPIB

Sampling  
Oscilloscope

- Read gate  
- Pulsed current  
sensors

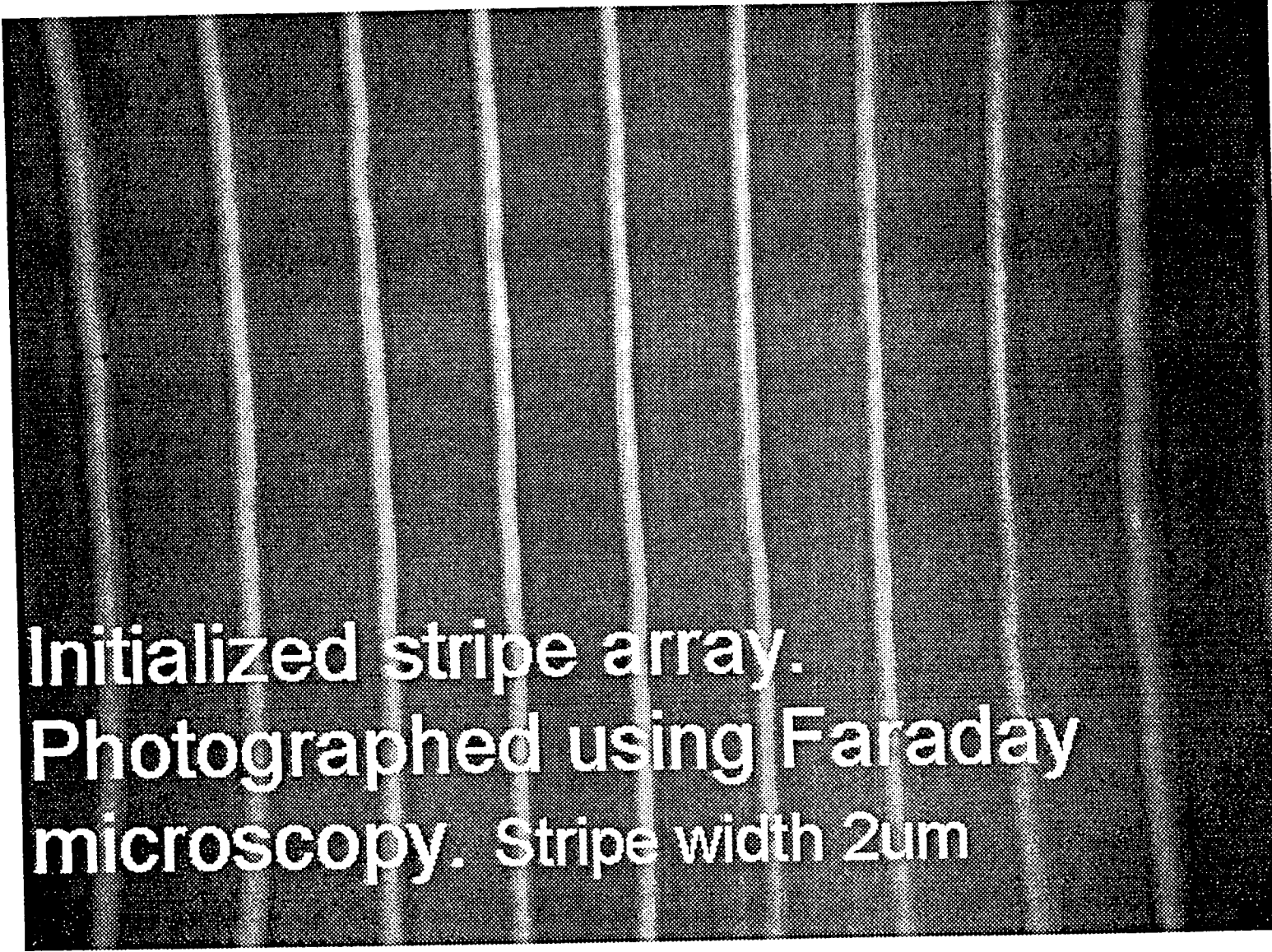
VBL memory chip interface

HP8110A  
2ch pulse generator

HP8110A  
2ch pulse generator

HP8110A  
2ch pulse generator

Latch



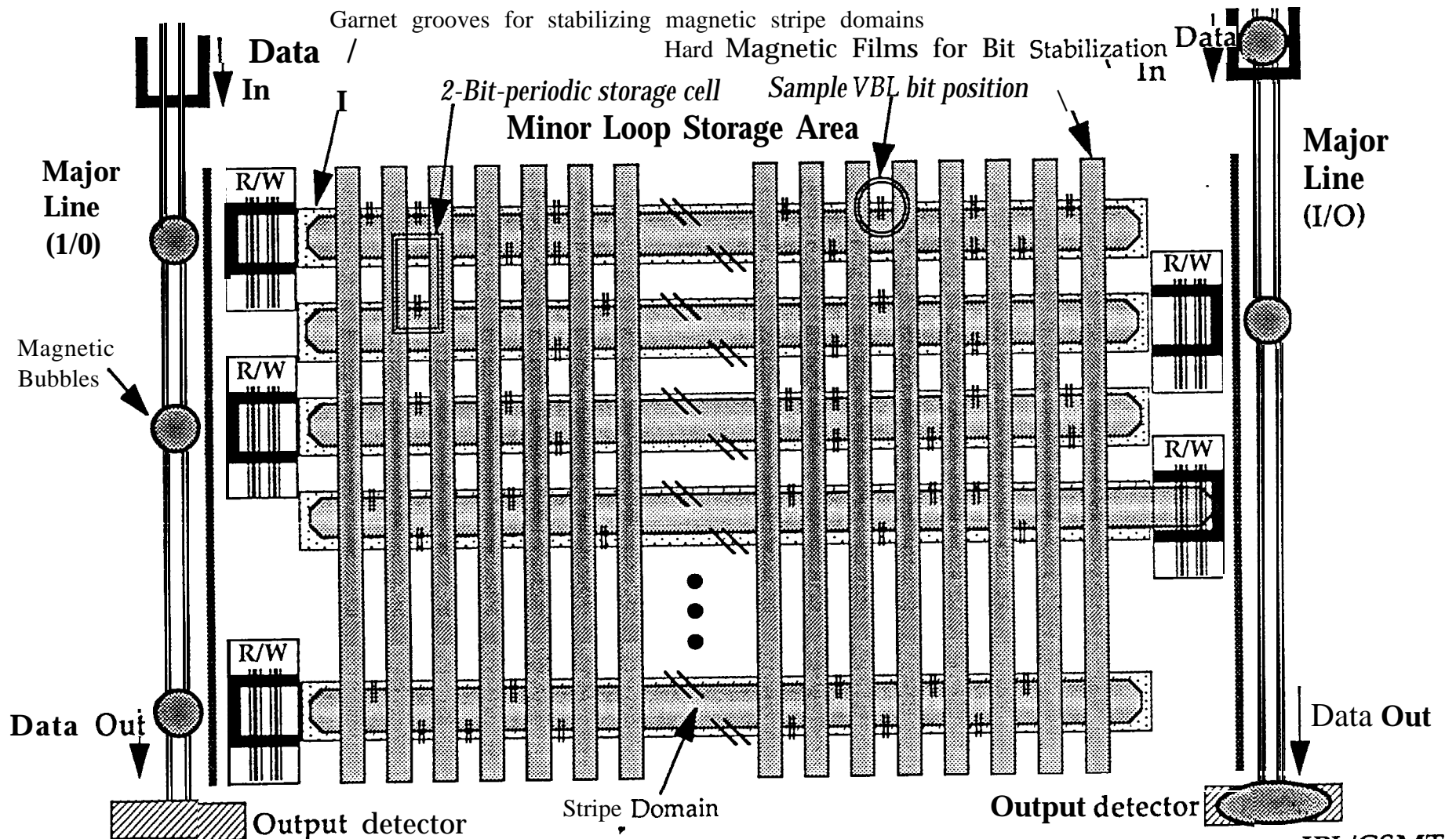
Initialized stripe array.  
Photographed using Faraday  
microscopy. Stripe width  $2\mu\text{m}$

# Potential Application to Spaceflight

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- Opportunities exist for demonstrating and validating new technologies in space to enable new space missions:
  - || Performance in space and Performance determined in space testing provides additional experimental data on magnetic device operation characteristics.
  - » Performance in space provides additional technology validation.
  - » Space applications provide requirements which have similarities to and differences from commercial requirements.
  - » The potential for addressing viability in space applications may be promising, such as through NASA's "New Millenium" program.

# A Sample Magnetic Device under Development: A VBL Data Storage Chip



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# Device Development Environments

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- Simulation tools, emulation tools, and statistical models written at a variety of levels support semiconductor device development.
- Standard layout descriptions (e.g., CIF) and standardized fabrication processes (e.g., MOSIS) support rapid prototyping and packaging of semicon
- A variety magnetic design tools and simulation tools exist for designing magnetic devices, such as electromagnetic field computation tools and Landau-Lifschitz-Gilbert equation solvers.
- Magnetic materials and device fabrication capabilities exist in a variety of universities, laboratories, and corporations
- Standardization of magnetic device descriptions and fabrication capabilities could greatly assist magnetic device development in analogy to that realized for semiconductor devices.

# Conclusions

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- Magnetic design and testing capabilities exist which can and are being used to develop and to investigate new magnetic devices.
- The possibility of investigating new device technologies for space applications offers the potential opportunity for validating new technologies while enabling and enhancing future space missions.
- An opportunity exists to define and to standardize magnetic device design tools, design layout descriptions, and fabrication processes to simplify and expedite magnetic device development.